

LaserSKI: Object Detection for Defect Detection in Semiconductors

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About dida



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Best paper award **ICML '21**



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Research

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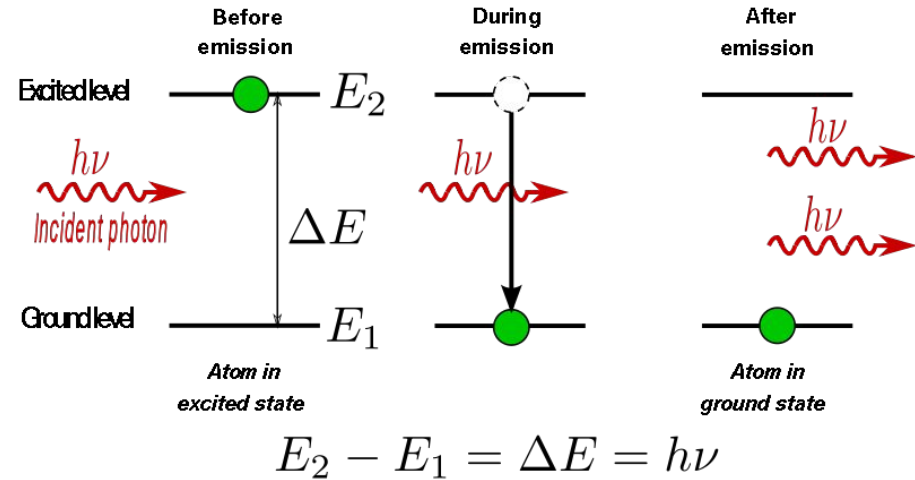
- ➔ ML research/application gap
- ➔ ML PoC trap

Agenda

- Intro to Diode Lasers
- Problem formulation and example data
- FasterRCNN Model
- Example results
- Possible extensions

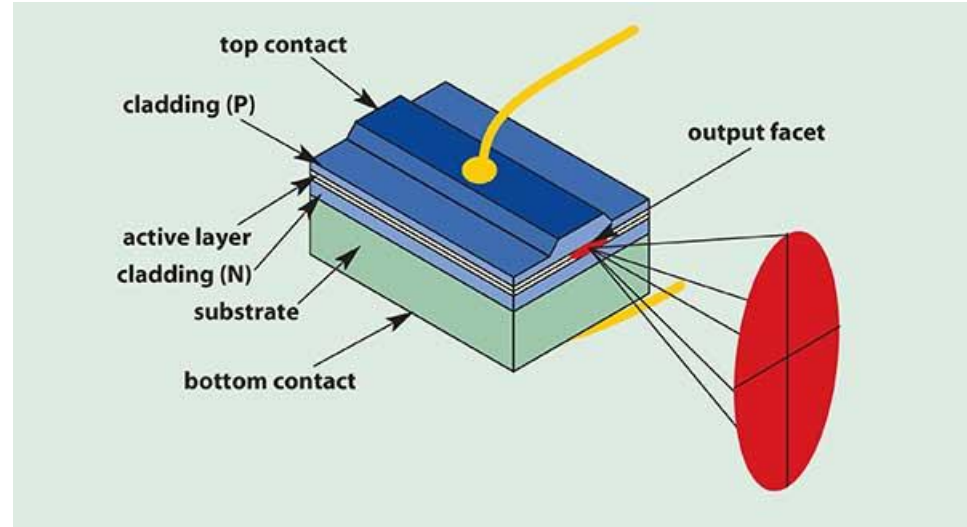
Lasers

- In a laser light is amplified by stimulated emission from a system that can exist in two states with different energies.
- In a diode laser this is achieved by using a junction between p and n type semiconductors.



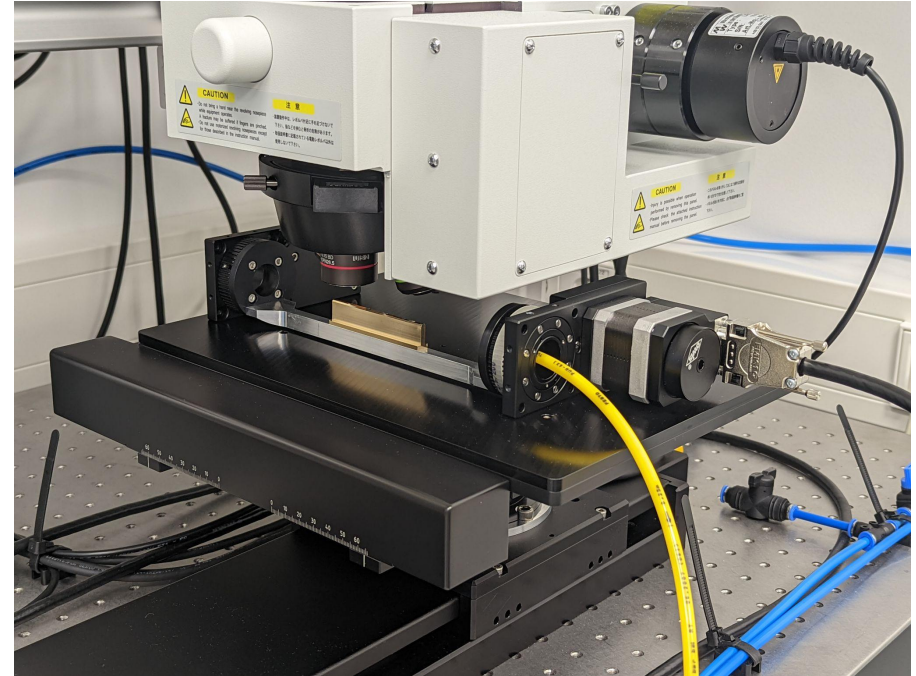
Diode Lasers

- In a P type semiconductor charge is conducted by “holes” with missing electrons
- In an N type semiconductor it is conducted by extra electrons
- A PN junction normally only lets charge through in one direction (this is a diode).
- When a voltage is applied in the “wrong” direction a photon can move an electron across and act as a laser



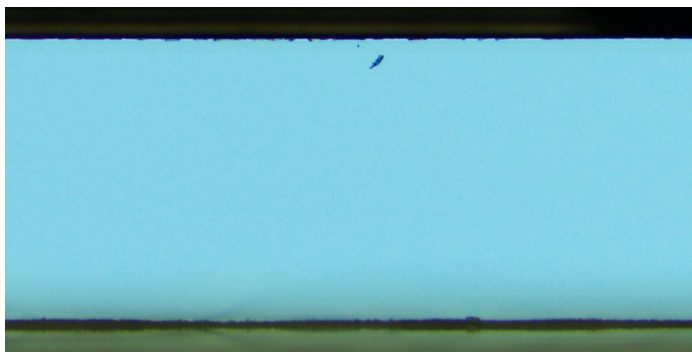
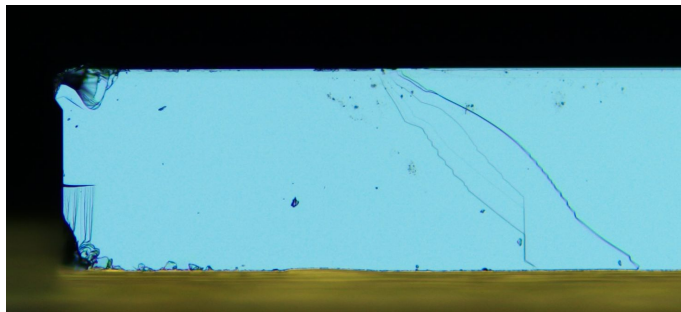
Problem formulation

- We want to find defects on both the “top” (p-side) and the front and back “edges” (facet)
- Images are taken using a microscope with a rotating assembly to allow access to all three axes.

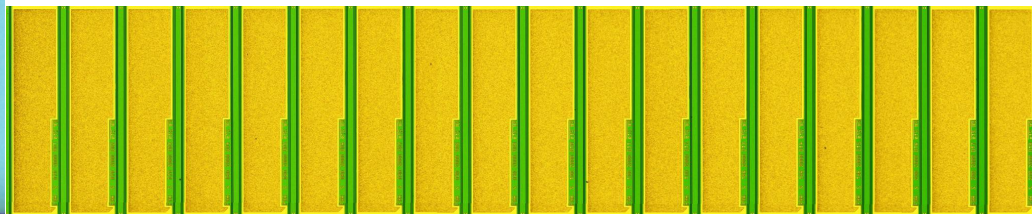
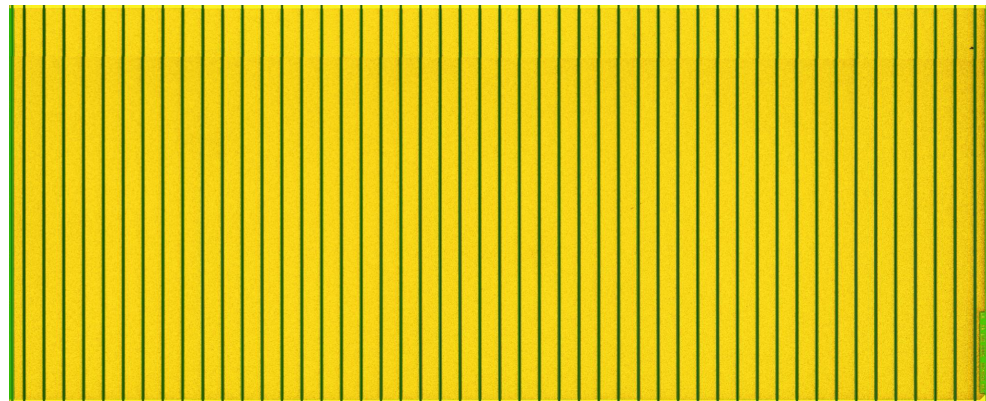


Data

(Front / Back) Facet

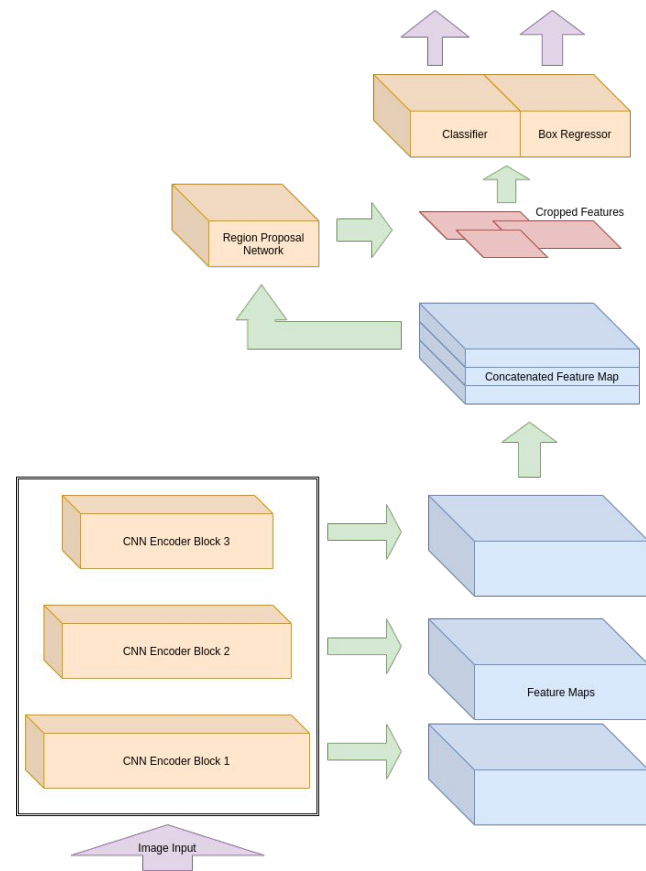


P-Side



Faster RCNN

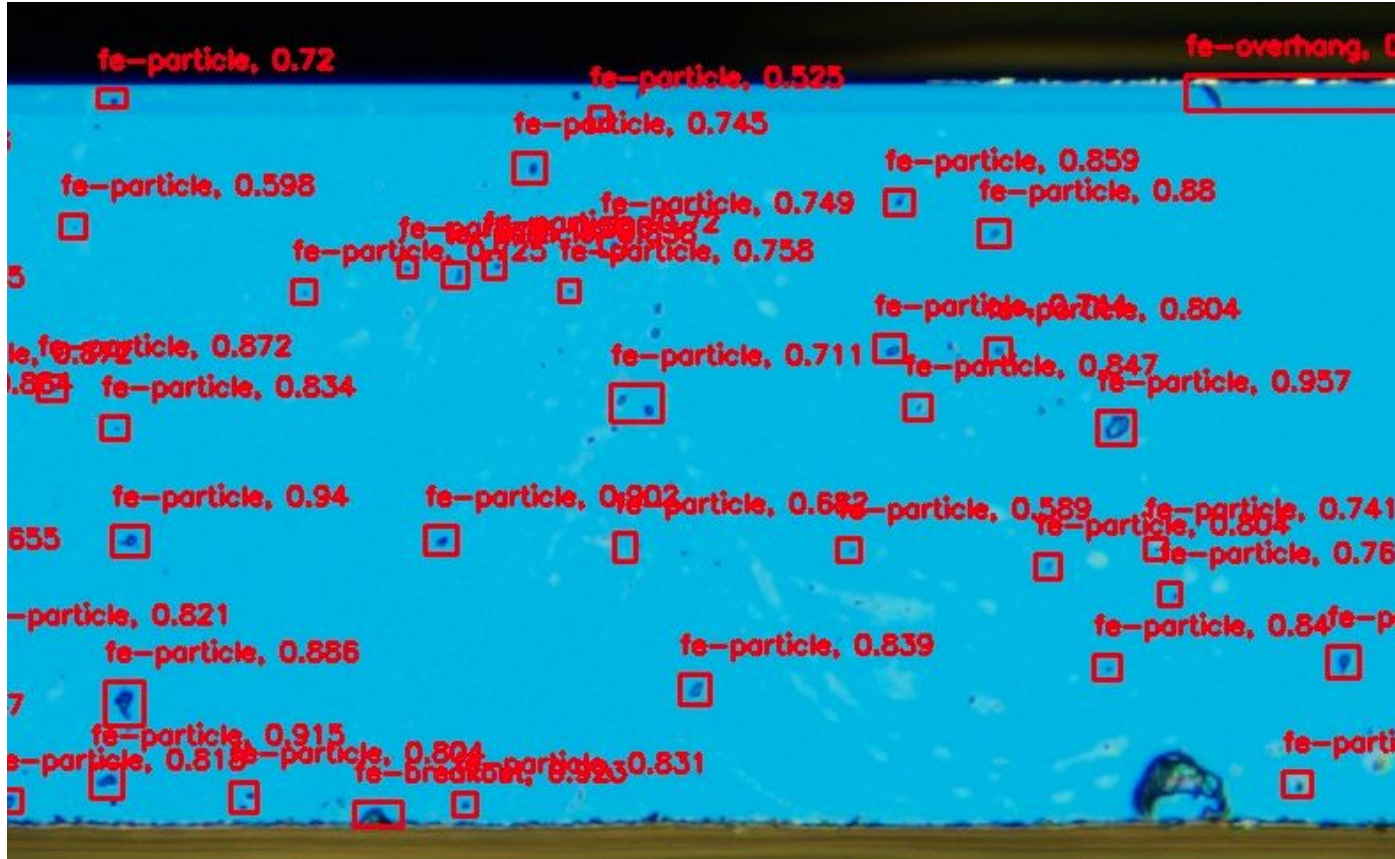
- Multi Scale feature maps are extracted from a CNN encoder.
- These are concatenated and fed into a CNN region proposal network to predict candidate regions.
- Classifier and bounding box regression networks are used to predict bounding boxes and classes.
- The network can use a pretrained encoder and be fine tuned end to end.



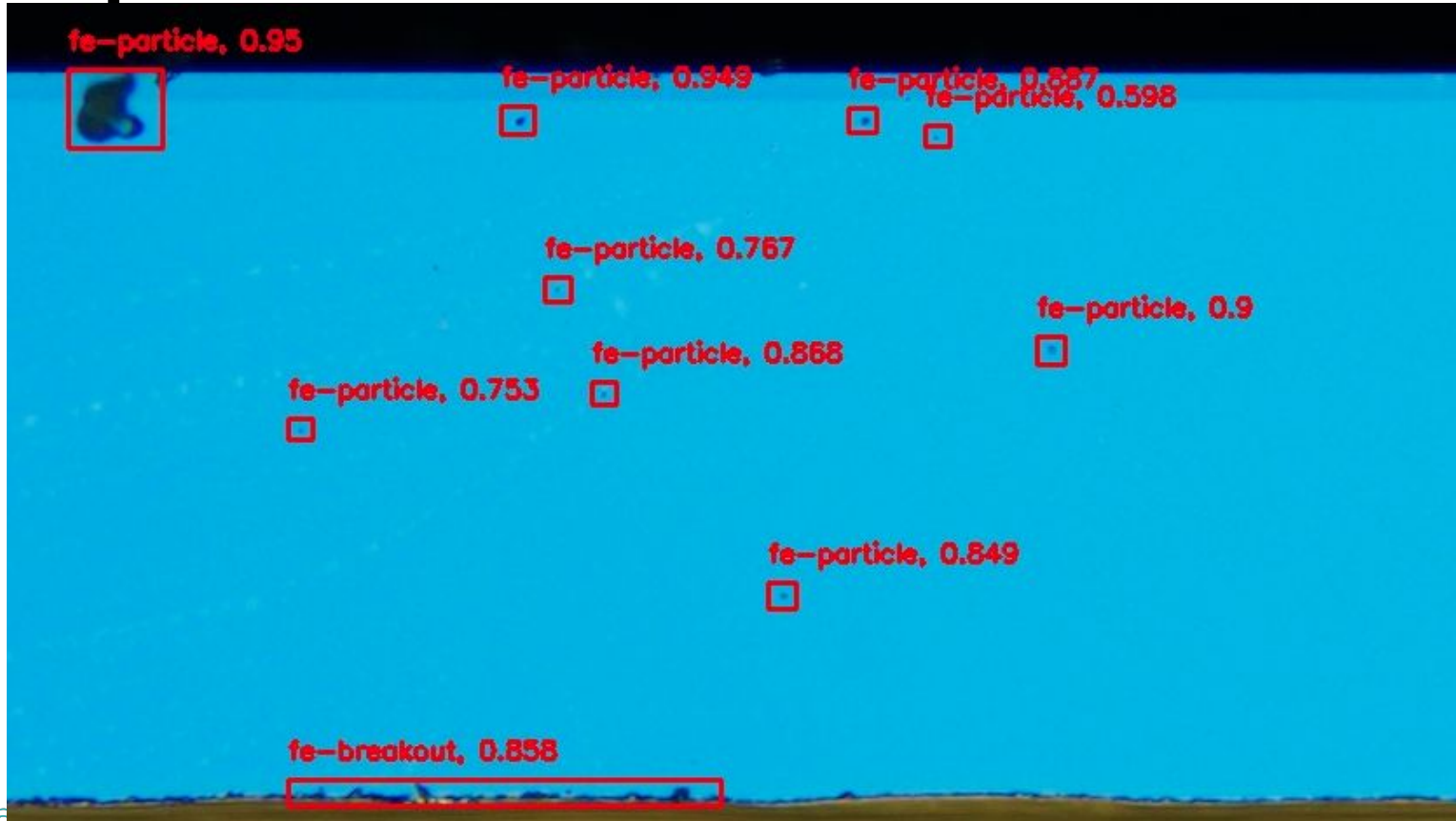
Implementation details

- Implemented in Pytorch Lightning
- Large dataset labeled by FBH 256
- Trained on 800x800 pixel chunks
- Metrics used were:
 - F1 50 | 50 (objectness threshold | intersection threshold)
 - mAP (Mean average precision at different thresholds)
- Boxes predicted across multiple chunks are sewn together

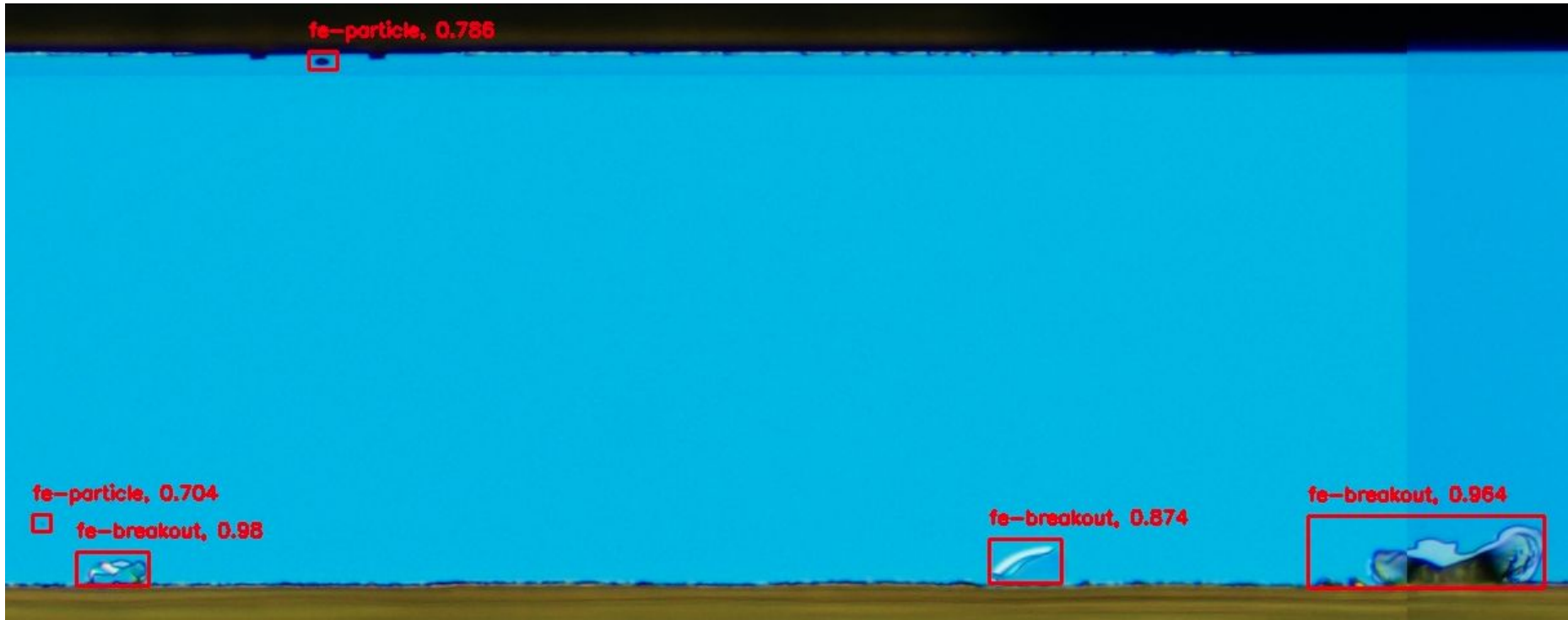
Example Results: Facet



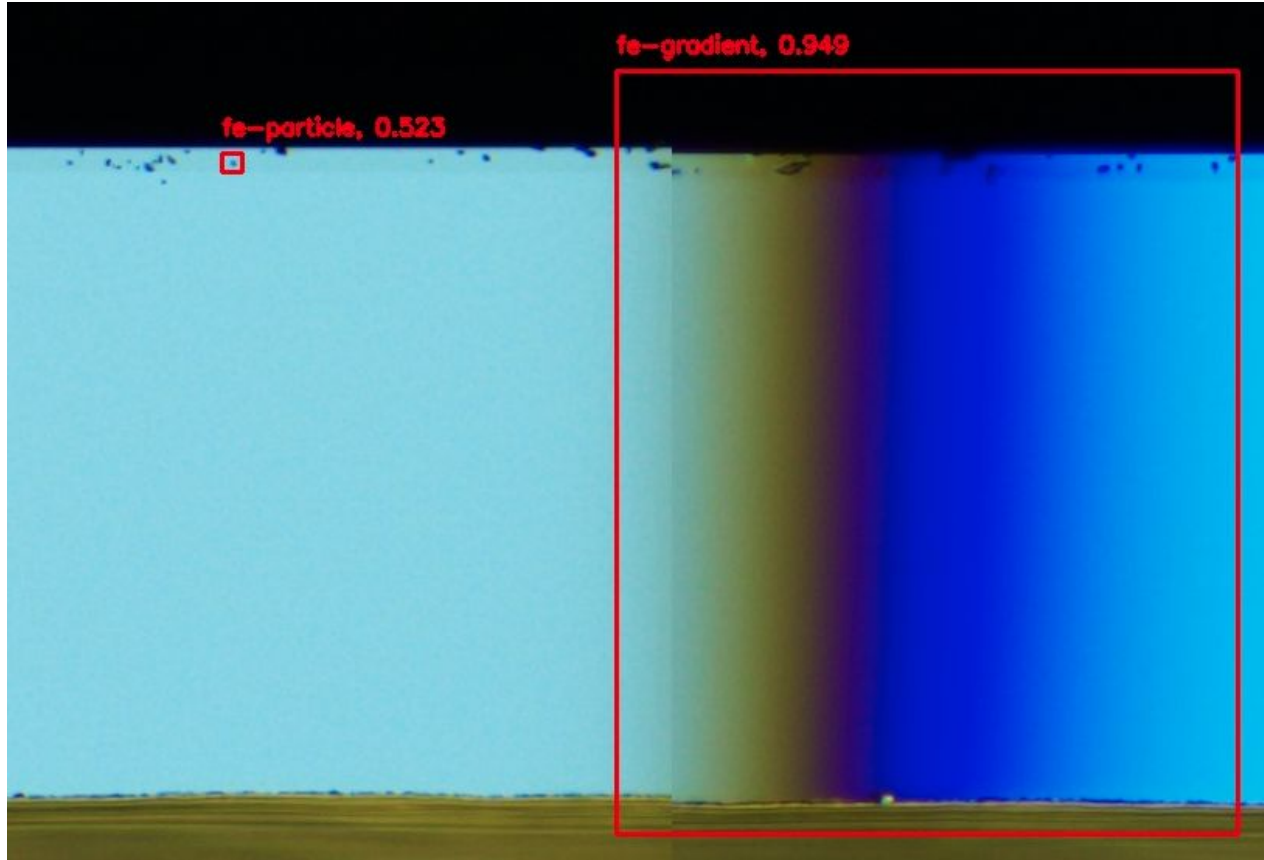
Example Results: Facet



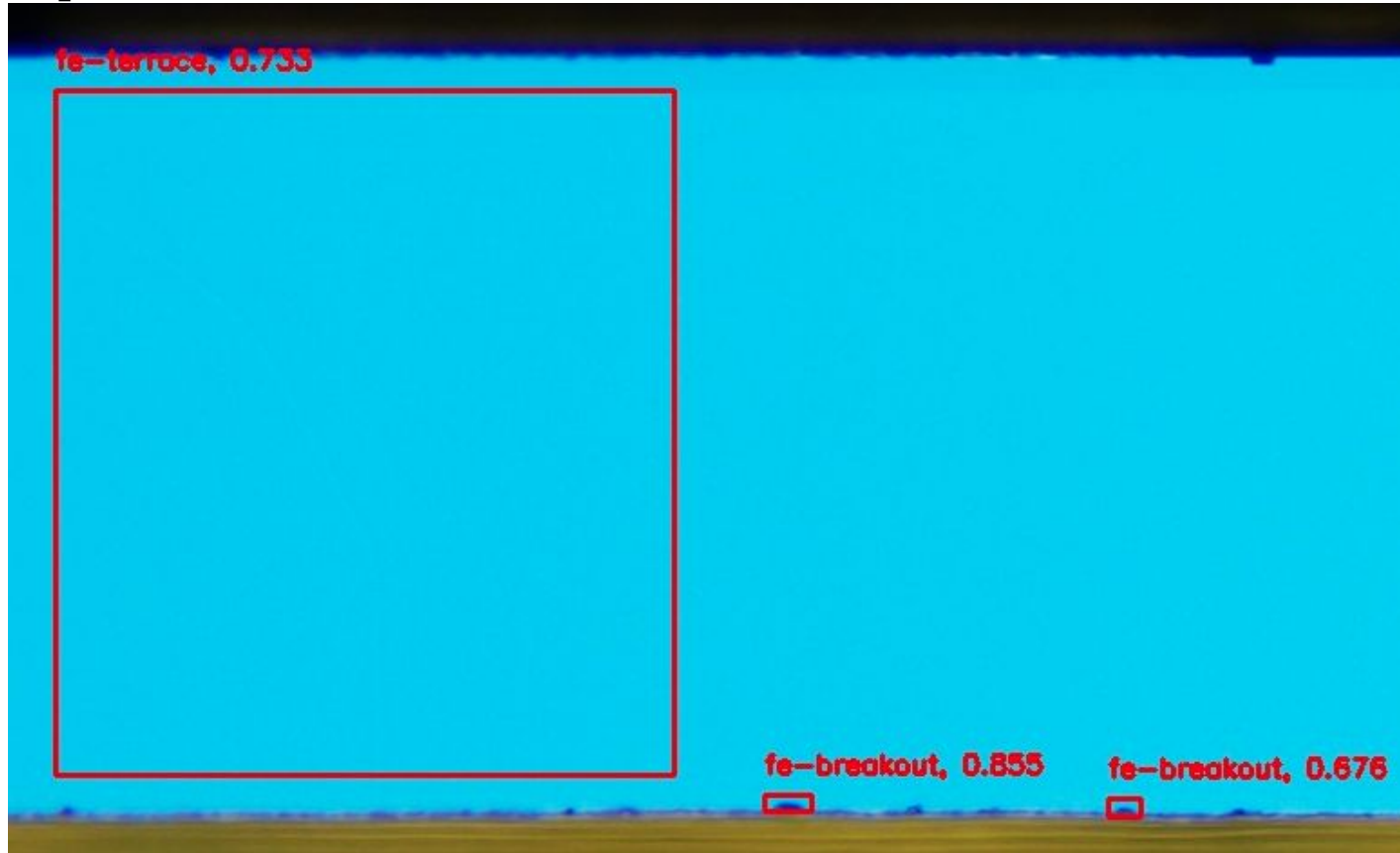
Example Results: Facet



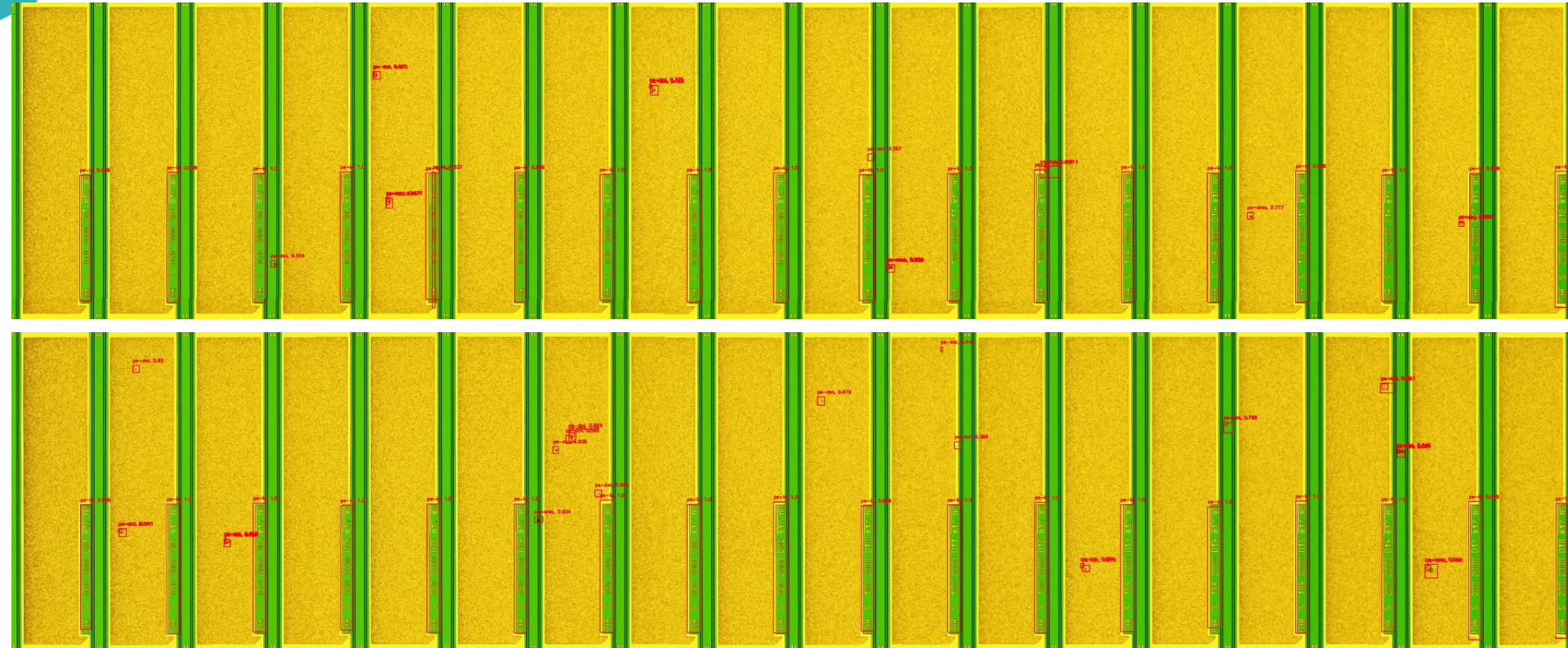
Example Results: Facet



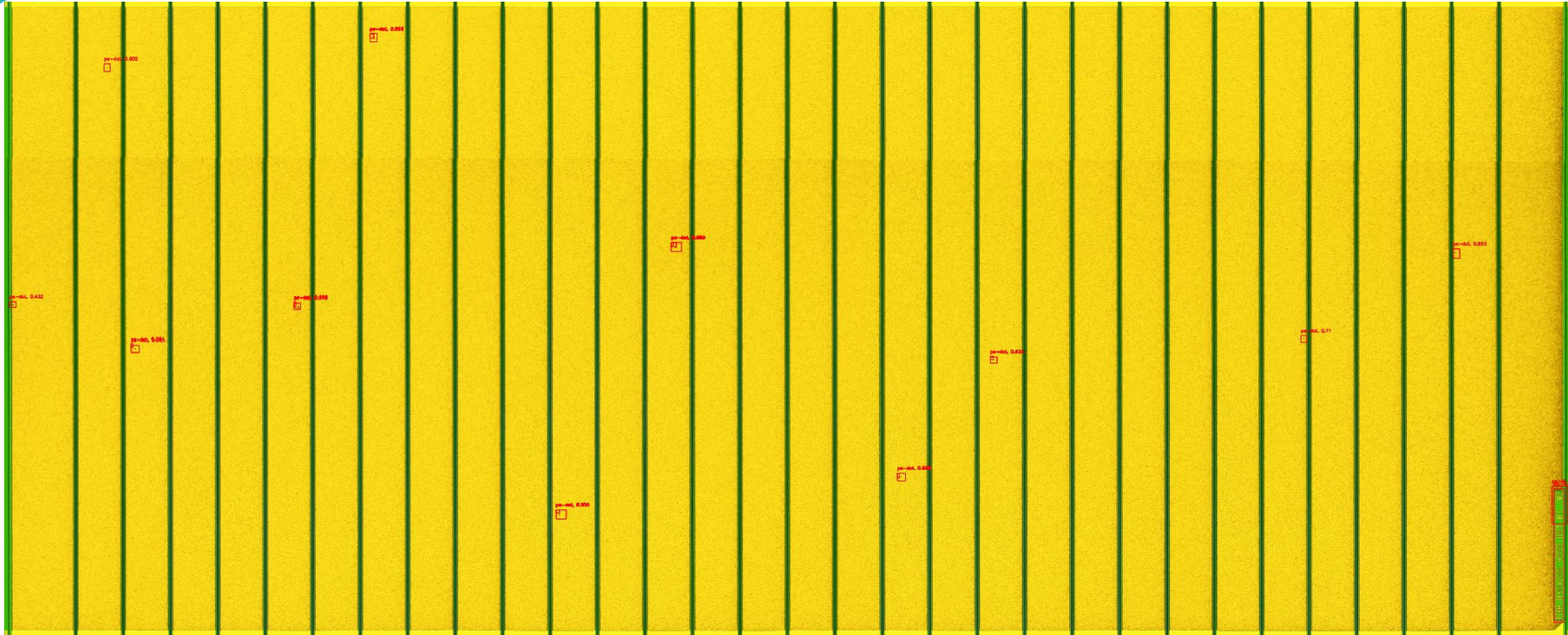
Example Results: Facet



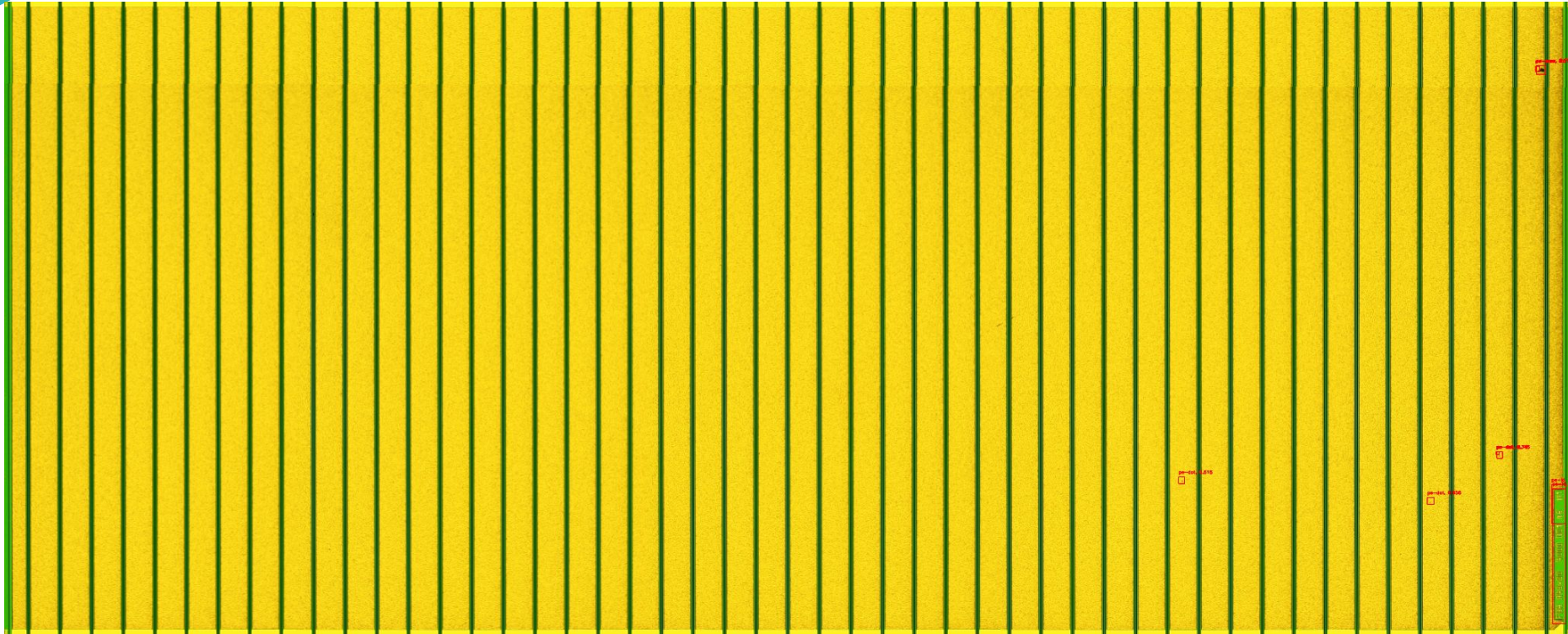
Example Results: P-side



Example Results: P-side



Example Results: P-side



Takeaways

- Object detection models are well suited for defect detection in semiconductors.
- The most common failure cases are:
 - Crowded regions
 - Multiple detections

Possible Extensions

- Move to segmentation:
 - Advantages
 - Easier to train
 - More precise information on defects
 - Disadvantages
 - More time consuming labelling
- Wrap the model in an active learning environment.